

Title (en)

PUMP APPARATUS FOR SEMICONDUCTOR PROCESSING

Title (de)

PUMPVORRICHTUNG ZUR BEHANDLUNG VON HALBLEITERN

Title (fr)

APPAREIL DE POMPAGE UTILISE DANS LE TRAITEMENT DES SEMI-CONDUCTEURS

Publication

EP 1934482 A2 20080625 (EN)

Application

EP 06815874 A 20060928

Priority

- US 2006038197 W 20060928
- US 24474405 A 20051006

Abstract (en)

[origin: US2007081893A1] The invention relates to a pump apparatus for use in semiconductor processing. The apparatus may include a single pump configured to transition a substance flow from about molecular pressure to about atmospheric pressure.

IPC 8 full level

F04D 29/04 (2006.01)

CPC (source: EP KR US)

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Citation (search report)

See references of WO 2007044260A2

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